

Electron Beam Evaporation System

Model: SA-VKE360

SA-VKE360 is a space-saving evaporation platform integrating electron beam and resistance thermal evaporation technologies. It features complete process functions, full automatic operation and low maintenance workload, catering to academic R&D experiments and small-volume pilot production.



Feature

- Low cost
- Lift-off
- Co-deposition
- High evaporation rate

Application

- Laser
- R&D
- Integrated circuit
- MEMS

Specifications:

Parameter	Descriptions
Number of Crucibles	6(max.)
Power Supply	10kW(max.)
Automatic Loadlocks	Single & multi-chip automatic loadlock
Workpiece Angle	-45°~45°, adjustable
Film thickness monitoring	Crystal oscillator controller
Ion Source	Hall ion source
Fixture types	Dome & Plate
Pumping System	Cryopump / magnetically levitated turbo-molecular pump + Dry mechanical pump
Coating Uniformity	±3%
Coating Repeatability	±2%
Uniform Deposition Area	Ø200 mm(max.)
Ultimate Vacuum	1E-5Pa
Vacuum Measurement	Full-range vacuum gauge
Temperature Control Range	-50~300℃
Space Requirements(L×W×H,m)	3.15×2.4×2.2

Principle:

